

MeV Electron Diffraction and Microscopy

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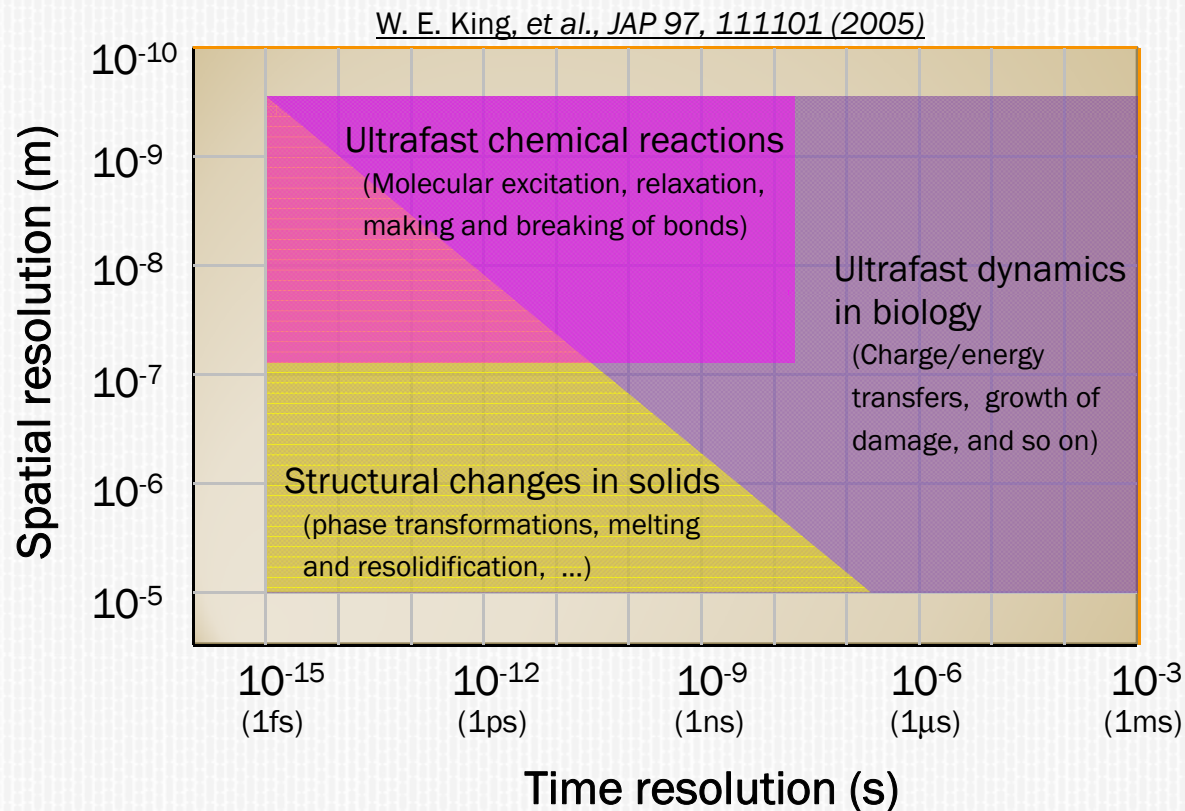
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R. Kuroda (AIST)

This work was supported by Grant-in-Aid for Scientific Research from JSPS!

Structural dynamics in matter

- ✓ Ultrafast phenomena or dynamics in materials are occurred on femtosecond time scales over atomic spatial dimensions.



- ✓ An ultrafast measurement with the resolution of **100 fs** & **sub-Angstrom** has long been in goal for the scientists.

Ultrafast detection techniques for study of ultrafast phenomena and dynamics

1) Ultrafast X-ray diffraction/image

Picosecond/femtosecond X-ray pulses generated from SR, FEL or laser plasmas acceleration have been used. **A powerful tool!**

→ big experiment/more expensive.

2) Ultrafast electron diffraction (UED)

In UED, a fs laser pulse is used as pump, while a fs or ps e^- bunch is used as probe. Recently, the time resolution has been achieved to 100 fs using DC or RF electron sources, **Very compact!**

but no spatial resolution!

3) Ultrafast electron microscopy (UEM)

UEM can observe the dynamics of structural transformation in nanometer (even atomic) spatial dimensions.

In UEM, the resolution has achieved to **10 ns** and **10 nm** with single-shot measurement.

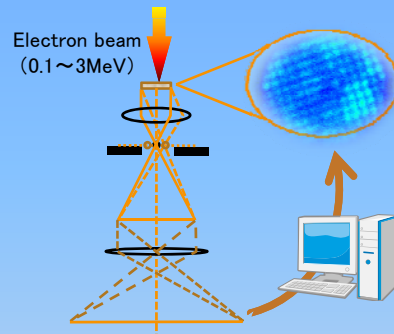
UEM and its applications



Imaging Technology

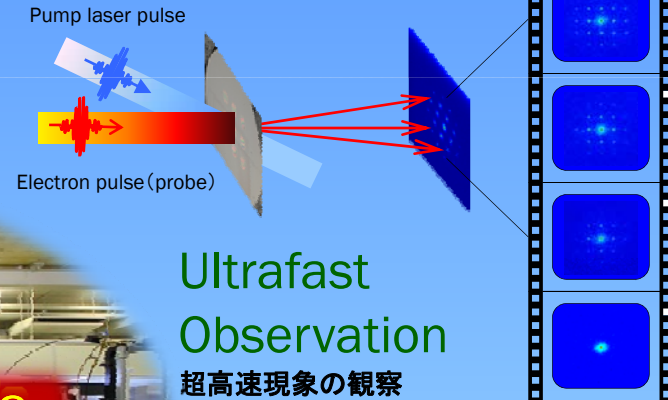
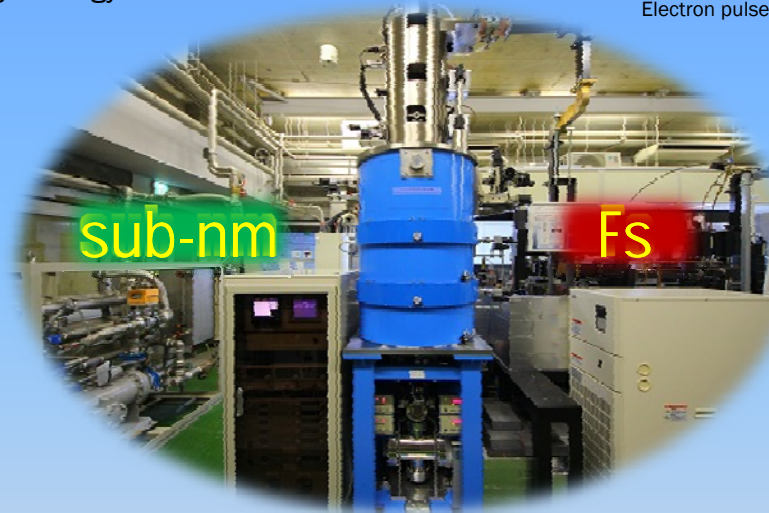
イメージング テクノロジー

Structural observation and imaging in “real space” with atomic-scale spatial resolution using high-energy electron beam.



Imaging in “real space”

Methods



Ultrafast Observation

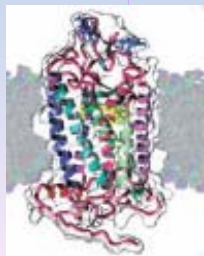
超高速現象の観察

Observations of fundamental dynamic processes in matter occurring on femto-second time scales over atomic spatial dimensions.

Observation in “real time”

Protein Structural Dynamics

タンパク質構造ダイナミクス

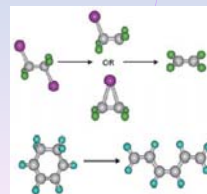


- Protein structural dynamics
- Macromolecular structure
- Reveal of functioning processes
- New technologies and applications in medical biology.

Targets

Making Molecular Movie

分子運動の可視化： - 新しい科学 -

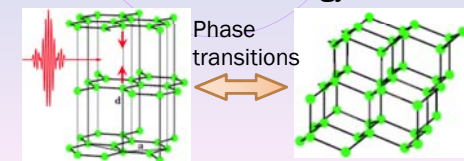


- Observation of single molecule motion.
- Ultrafast chemical reactions
- Solvation dynamics
- Discovery of transition states and reaction intermediates.

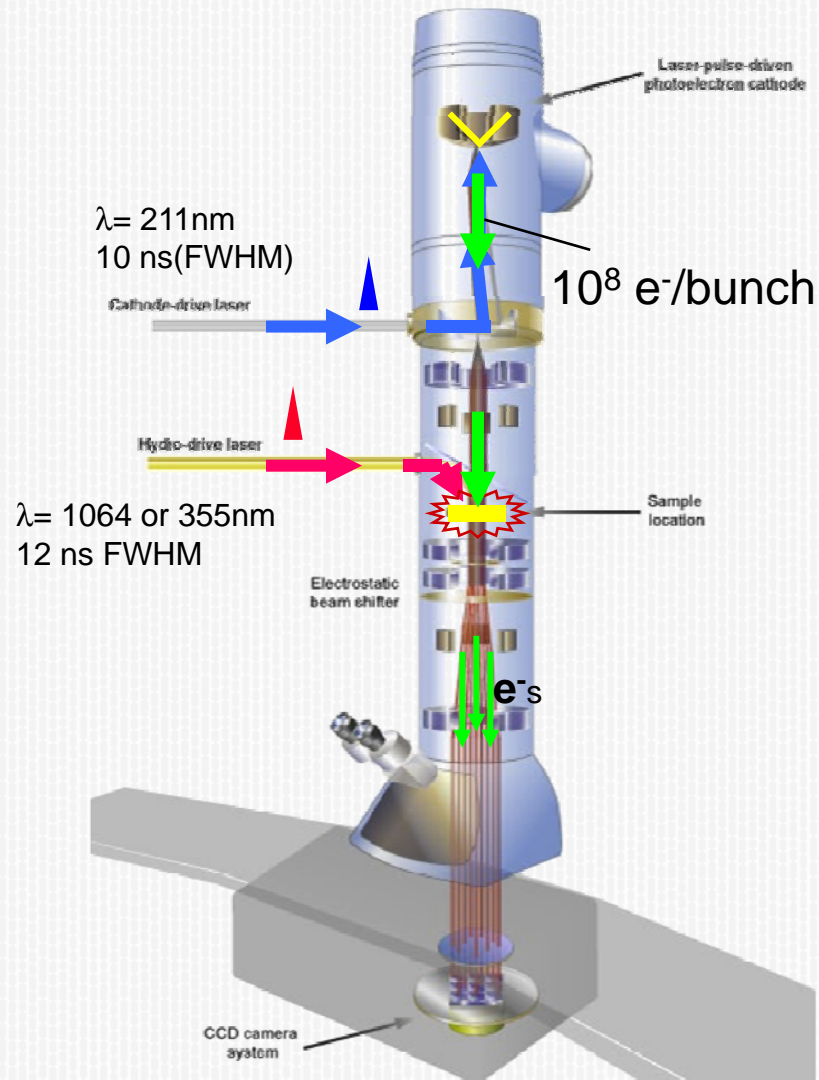
Nano-technology/science

ナノテクノロジー・サイエンス

- Transformation dynamics of novel nano-scale materials.
- Creation of new functional materials and devices for nanotechnology.

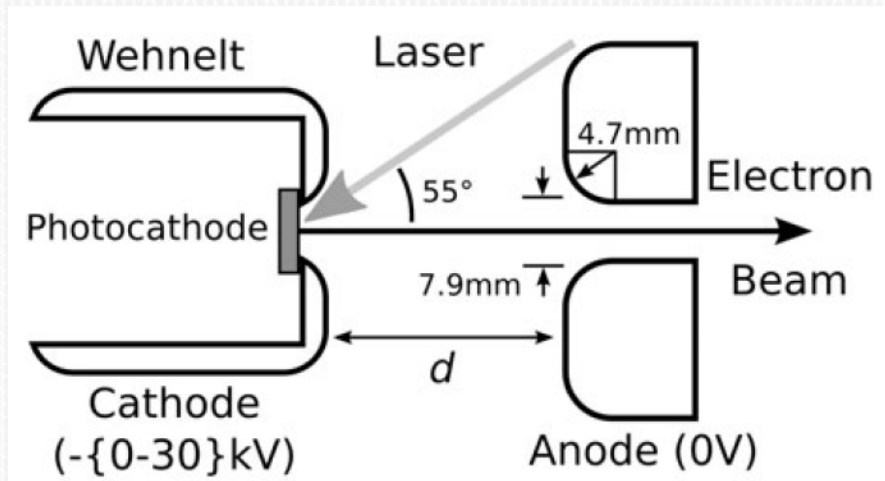


Recent UEMs



B. W. Reed, Workshop on UESDM, 2012

photocathode DC gun in UEMs



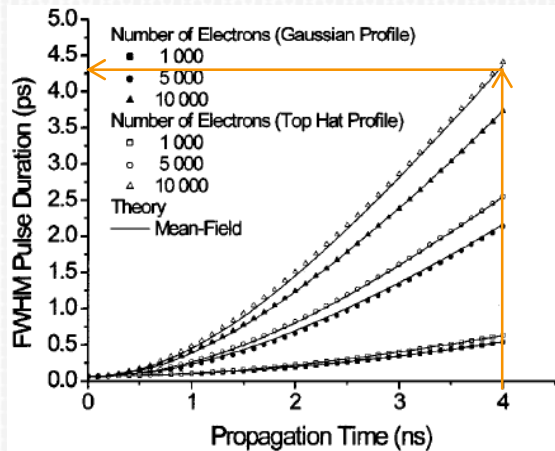
- keV-energy electron pulses with $\sim\text{ns}$ & $10^8\text{ e}^-/\text{pulse}$ for single-pulse imaging.
- keV-energy single-electron pulses for stroboscopic measurement.



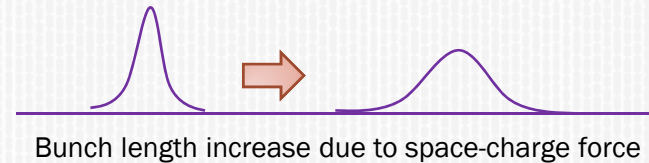
UEM is a powerful technique
for study of structural dynamics!

Space-charge problem in recent UEM

1) Increase of bunch length during beam transport



B. J. Siwick et al., JAP 92, 1643(2002)

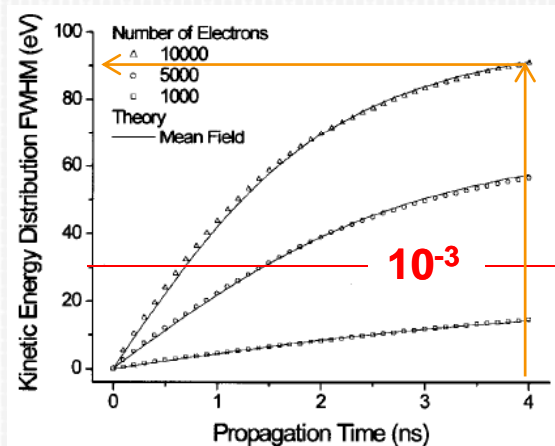


$$\Delta t \approx \Delta t_0 + \frac{Ne^2 t_2}{2\pi r^2 \epsilon_0 m v}$$

$\Delta t = 300\text{fs} \rightarrow 4\text{ps}$ during the 40cm transport of 30keV e^- beam

It is difficult to generate a high-intensity and fs-pulse electron beam in keV energy region!

2) Increase of energy spread during beam transport



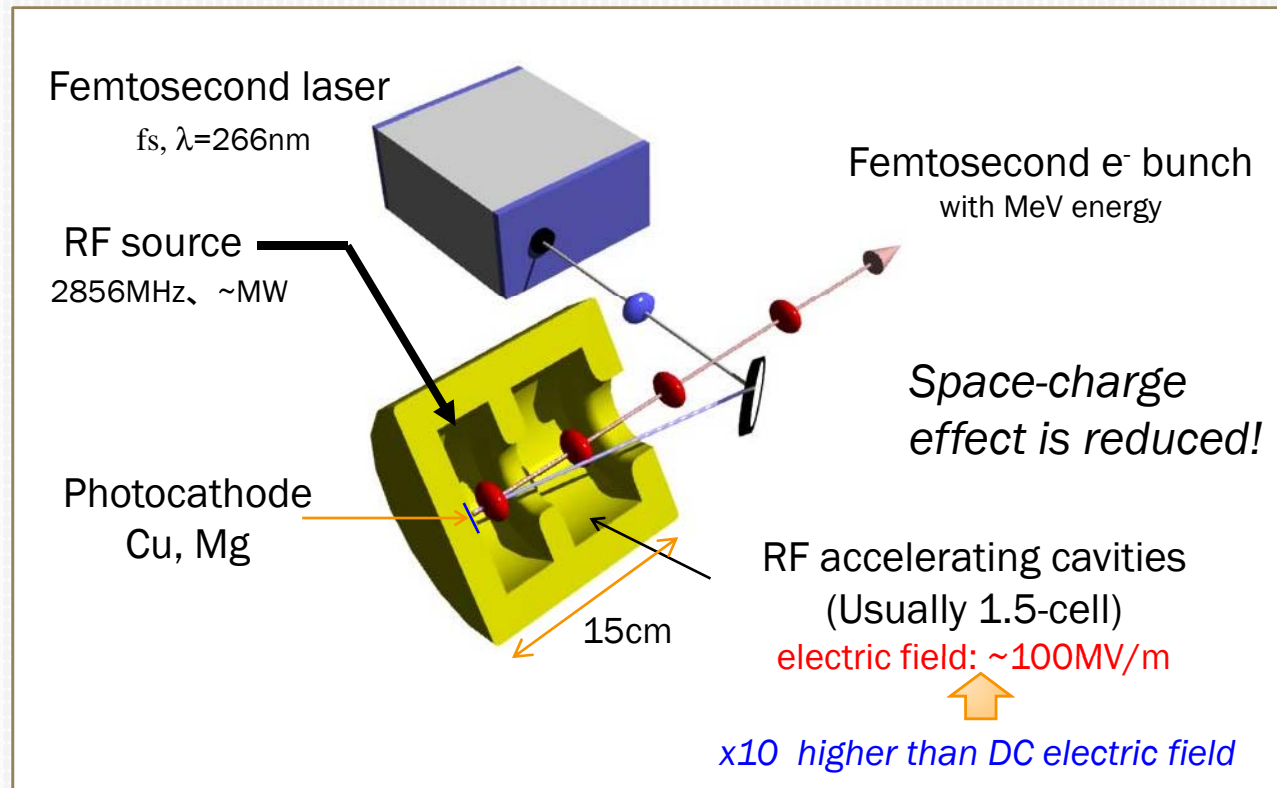
$$\Delta E_k \approx m v_0 \Delta v = m v_0 \frac{dl}{dt}$$

$\Delta E/E \rightarrow 3 \times 10^{-3}$ during the beam transport

One solution of the space-charge problem is to increase the beam energy!

a choice to use a RF MeV electron gun in UEM

What radio-frequency (RF) electron gun?



The expected beam parameters:

Electron energy:	1~3 MeV
Bunch length:	100 fs
Emittance:	0.1 mm-mrad
Energy spread:	10^{-4} (10^{-5} for challenge)
Charge:	$10^7 \sim 10^8 e^-$'s/pulse

} Key parameters for EM!
How to generate such beam?

Beam dynamics in RF gun

1) Longitudinal dynamics

RF field in longitudinal direction:

$$E_z = E_0 \cos kz \sin(\omega t + \phi_0)$$

$$\phi = \omega t - kz - \phi_0 = k \int_0^z \left(\frac{\gamma}{\sqrt{\gamma^2 - 1}} - 1 \right) dz + \phi_0$$

$$\frac{d\gamma}{dz} = \frac{eE_0}{2mc^2} [\sin \phi + \sin(\phi + 2kz)]$$



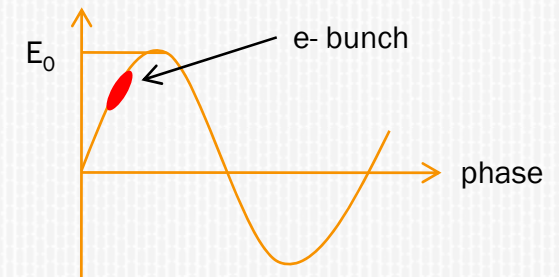
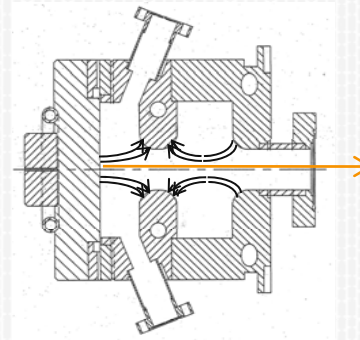
Kim, NIM A275, 201-218(1989)
Travier, NIM A340, 26-39(1994)

$$\gamma = 1 + (n + 0.5)\alpha\pi = 1 + 146.8(n + 0.5) \frac{E_0[MV/m]}{f[MHz]}$$

$$\sigma_{\Delta\gamma}(rms) = 2\pi\alpha f \sigma_z = 2.9 \times 10^{-4} E_0[MV/m] \sigma_z[ps]$$

$$\left. \frac{\Delta E}{E} \right|_{RF} (rms) = \frac{\sigma_{\Delta\gamma}}{\gamma - 1} = 2 \times 10^{-6} \frac{f[MHz] \sigma_z[ps]}{n + 0.5}$$

$$\alpha = \frac{eE_0}{2mc^2 k} = 46.7 \frac{E_0[MV/m]}{f[MHz]}$$



Example:

$E_0 = 25 \sim 100 MV/m$, $f = 2856 MHz$, 1.5-cell



Energy: 1~4 MeV

- using 100fs laser,
 $\Delta E/E \sim 10^{-4}$
- using 10fs laser,
 $\Delta E/E \sim 10^{-5}$

Beam dynamics in RF gun

2) Transverse dynamics

Emittance due to space-charge effect:

$$\mathcal{E}_{x,z}^{sc} = \frac{\pi}{4} \frac{1}{\alpha k} \frac{1}{\sin \phi_0} \frac{I_p}{I_A} \mu_{x,z}$$

Gaussian distribution beam

$$\mu_x = \sqrt{\langle \Gamma_x^2 \rangle \langle x^2 \rangle - \langle \Gamma_x x \rangle^2} = \frac{1}{3\sigma_x / \sigma_z + 5}$$

$$\mathcal{E}_x^{sc} [mm-mrad] = 3.76 \times 10^3 \frac{Q[nC]}{E_0[MV/m](2\sigma_x[mm] + \sigma_z[ps])}$$

Emittance due to RF effect:

$$\mathcal{E}_x^{rf} = \sqrt{\langle p_x^2 \rangle \langle x^2 \rangle - \langle p_x x \rangle^2} = \alpha k \langle x^2 \rangle \sqrt{\langle \sin^2 \phi_f \rangle - \langle \sin \phi_f \rangle^2}$$

$$\phi_f \rightarrow \langle \phi_f \rangle + \Delta \phi, \quad \langle \phi_f \rangle = 90^\circ$$

$$\mathcal{E}_x^{rf} = \alpha k^3 \frac{\sigma_x^2 \sigma_z^2}{\sqrt{2}}$$

$$\mathcal{E}_x^{rf} = 2.73 \times 10^{-11} E_0 f^2 \sigma_x^2 \sigma_z^2$$

$$\mathcal{E}_x^{rf}: mm \cdot mrad$$

$$E_0: MV/m, \quad f: MHz$$

$$\sigma_x: mm, \quad \sigma_z: ps$$

Example:

$$E_0 = 100 MV/m, \quad f = 2856 MHz, \quad Q = 1 pC,$$

$$\sigma_x = 0.1 mm, \quad \sigma_z = 100 fs$$

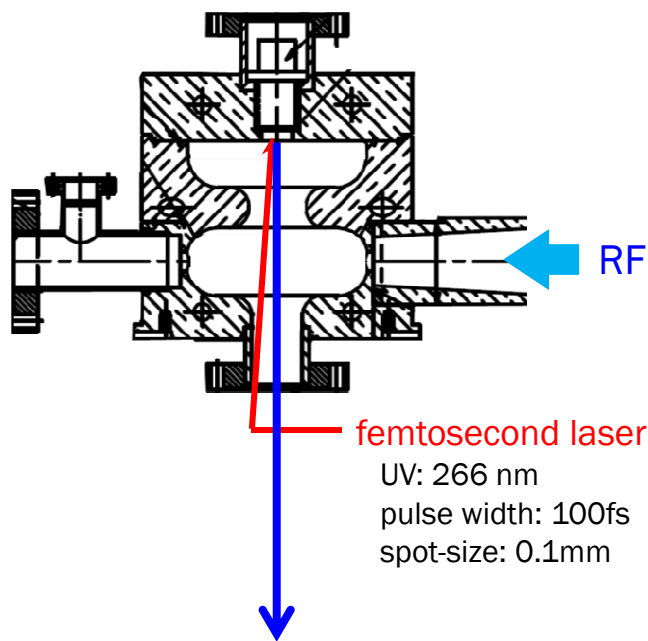


$$\mathcal{E}^{sc} \sim 0.1 \text{ mm-mrad}$$

$$\mathcal{E}^{rf} \sim \text{negligible}$$

The emittance is dominated by thermal emittance for low-charge e- beam!

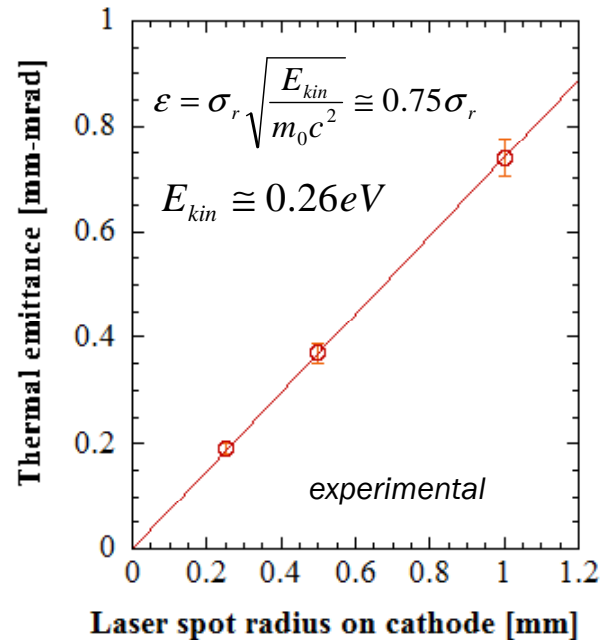
Generation of high-brightness e⁻ beam with RF gun



Femtosecond electron beam

Emittance: 0.1 μm
Energy spread: 10^{-4}

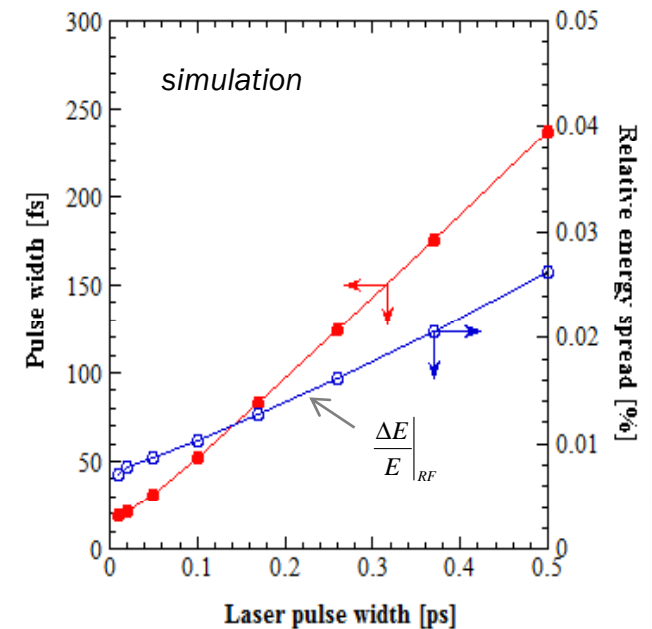
Emittance as a function of laser spot radius on Cu cathode



- ✓ reduce thermal emit. with small size laser
 $\varepsilon_{th} \sim 0.1 \text{ mm-mrad}$ at $\sigma_r = 0.1 \text{ mm}$
- ✓ Initial energy spread emitted from Cu cathode

$$\left. \frac{\Delta E}{E} \right|_{in} = \frac{E_{kin}}{E} \approx 10^{-4}$$

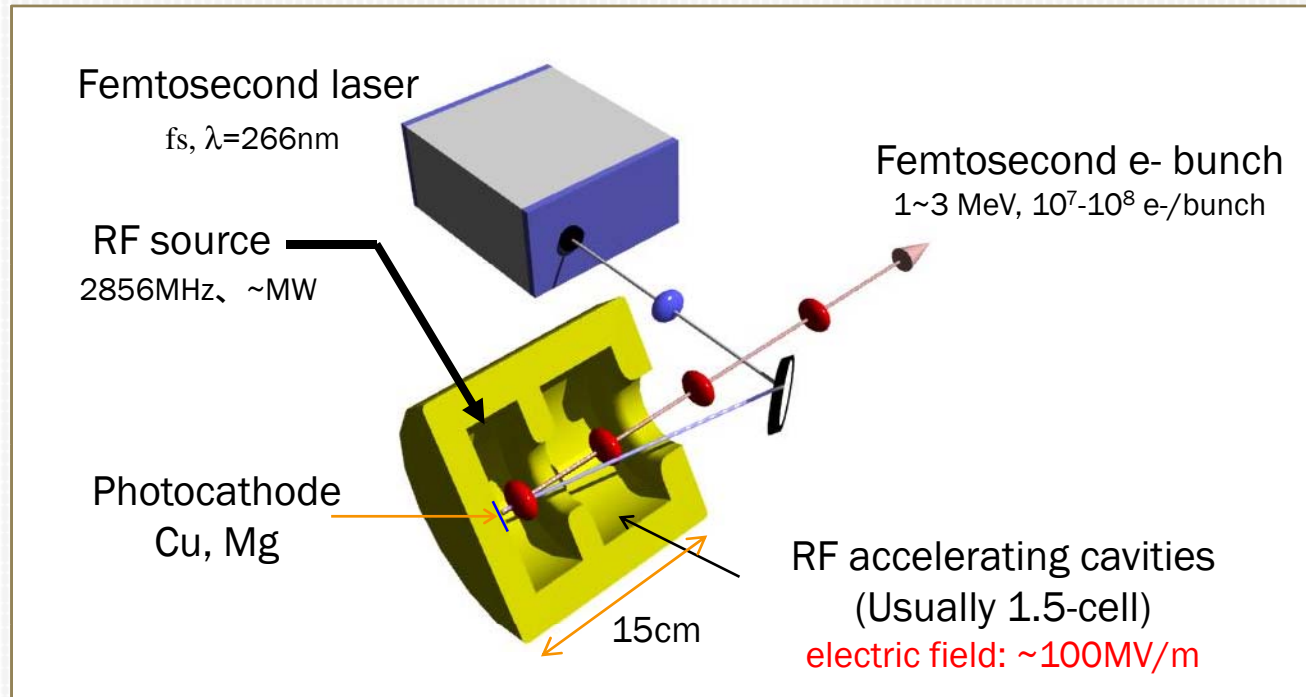
Energy spread as a function of laser pulse width



- ✓ reduce energy spread due to RF effect with short-pulse laser

$$\Delta E/E \sim 10^{-4} \text{ at } \sigma_z < 100 \text{ fs}$$

RF gun based UED in world



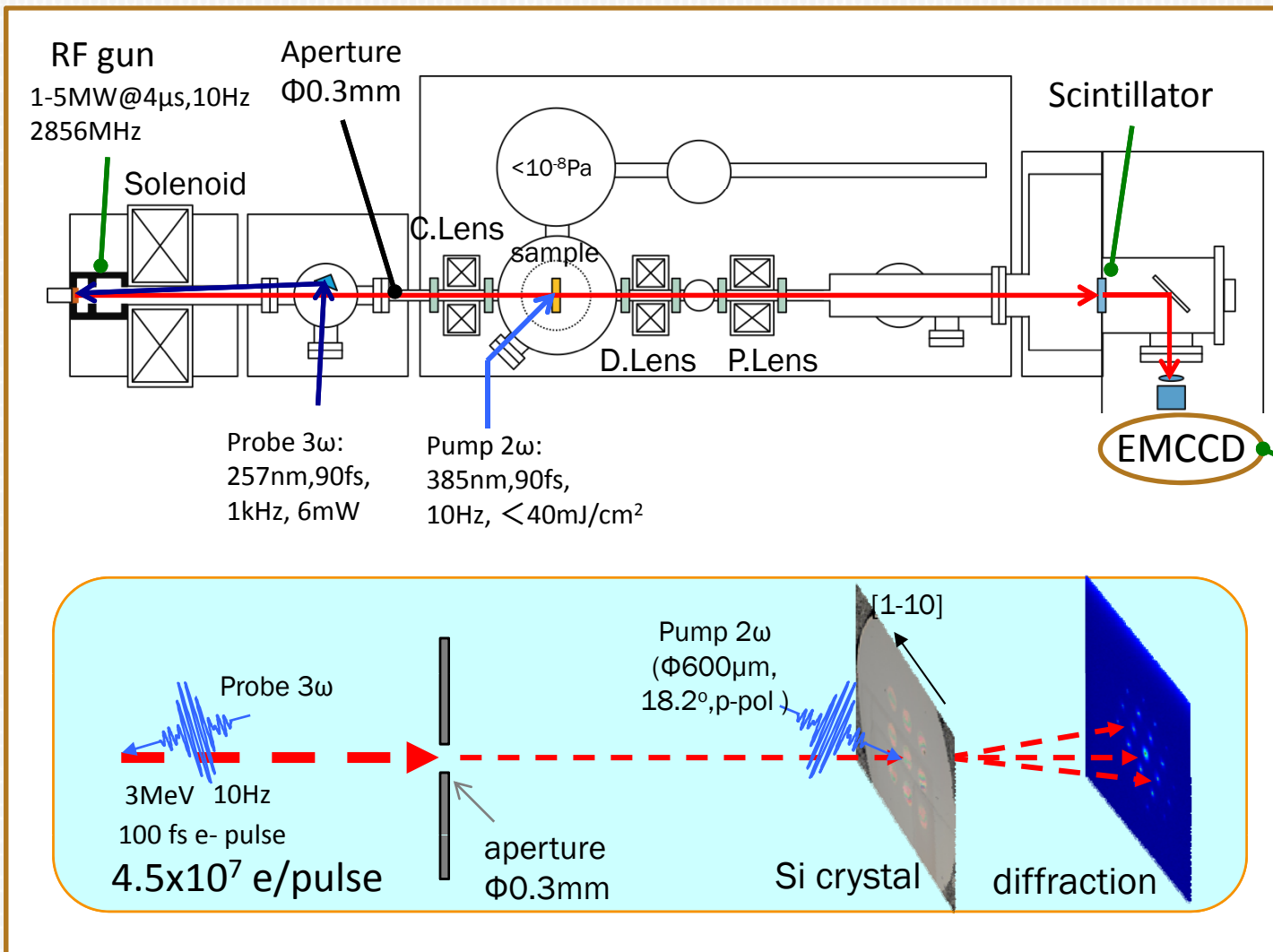
Recently, the RF gun has been successfully used/proposed in UED facilities at BNL, SLAC, UCLA, Tsinghua Univ. , Osaka Univ., DESY, Shanghai Jiaotong Univ., KAERI, ...

Ultrafast electron diffraction at Osaka University

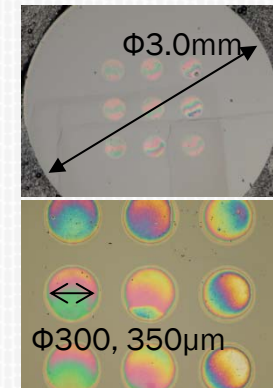
Electron energy: 1~3 MeV
Time resolution: 100 fs

RF gun based MeV UED at Osaka Univ.

use of electron optical lenses as like in electron microscopy



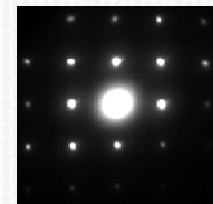
Sample



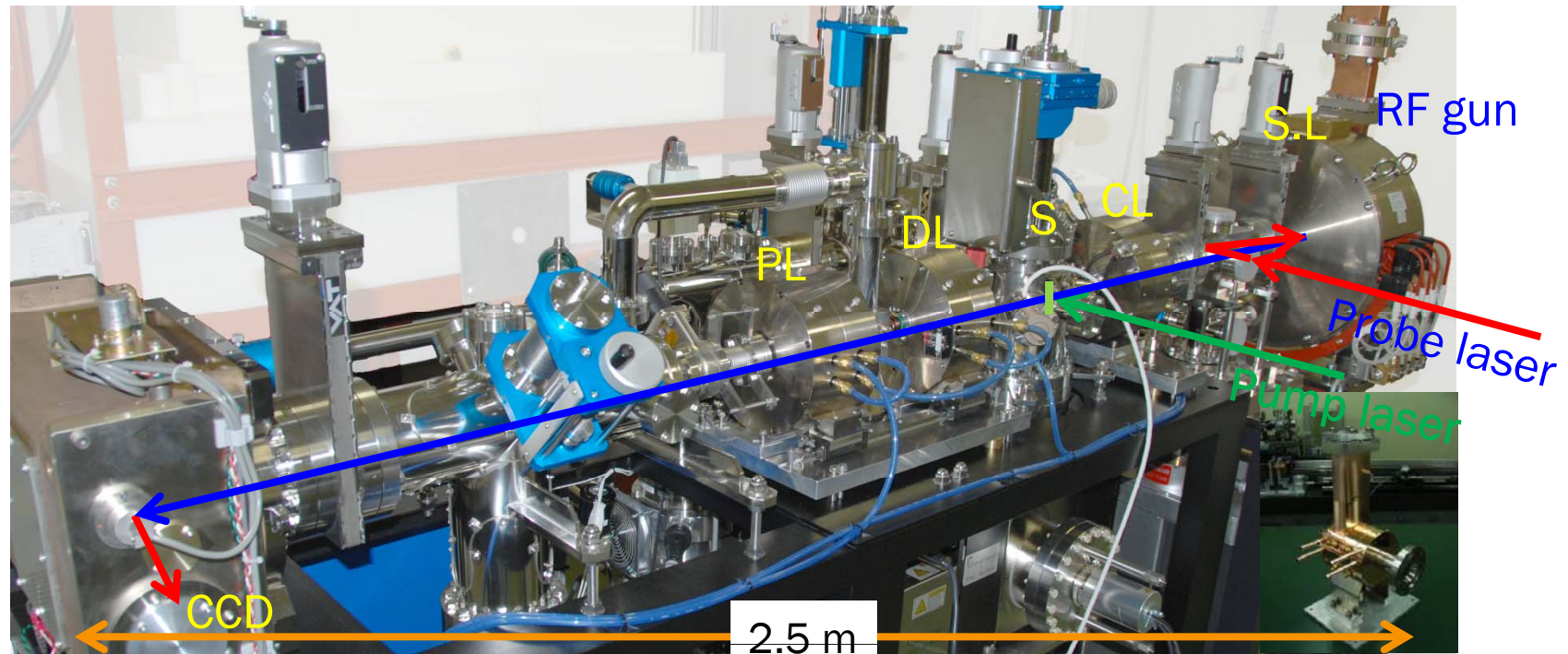
CsI (Tl) scintillator
Area: 5x5cm



Diffraction



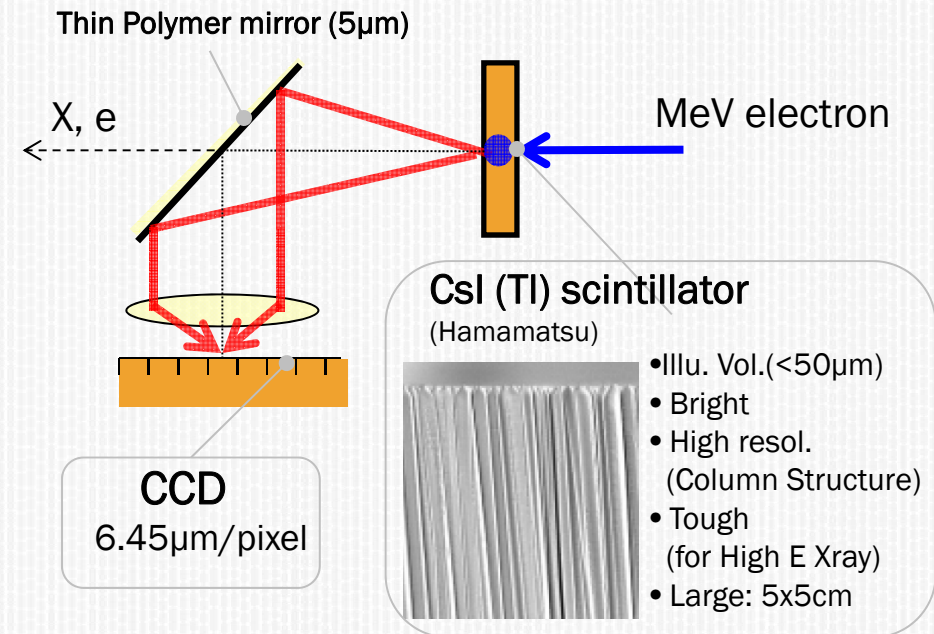
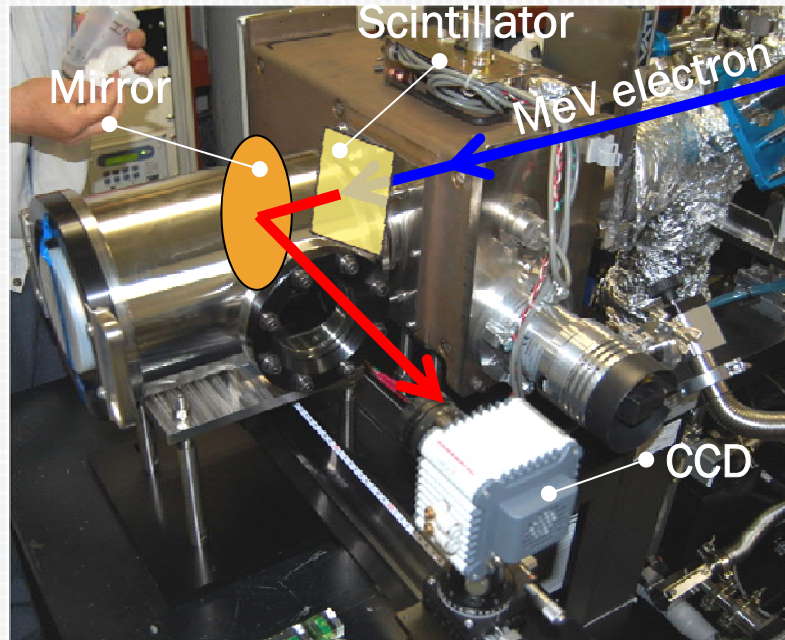
Picture of UED system at Osaka Univ.



use of electron optical lenses, therefore, compact.

Detection of MeV electron diffraction

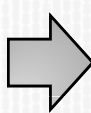
Requirements of MeV electron detector: high resolution, high efficiency, no damage



Problems

- Very low current, i.e. ~pA
- Small scattering angle, i.e. 0.1mrad
- Strong X-ray emissions, i.e. Backgnd, pixel defect
- Damage by MeV electron, i.e. scintillator, fiber
- Diff. Pattern to be magnified/shifted

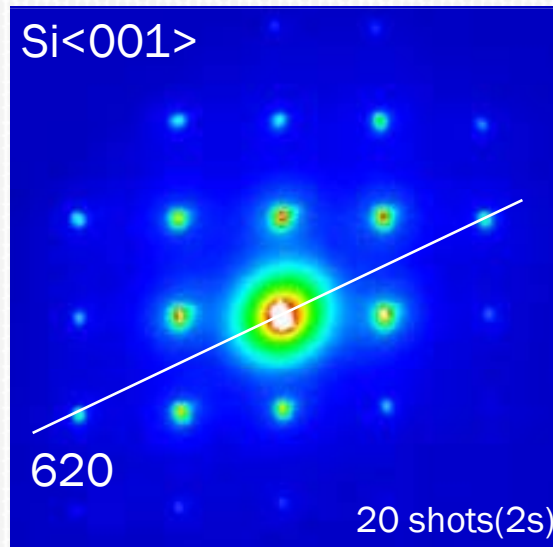
Solution

- 
- CsI: Small Illumination volume size-matched to CCD pixel
 - Indirect exposure
Thin mirror + Lens coupling
 - No pixel defect observed yet
 - Large detection area, i.e. 5x5cm²

Quality of MeV electron diffraction

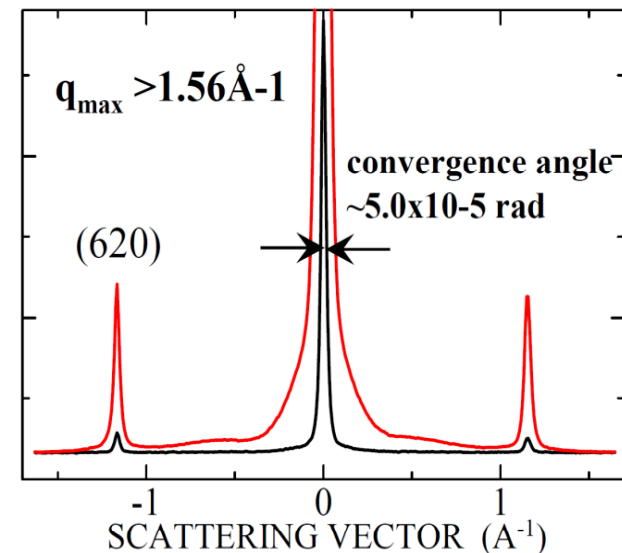
Electron beam: 3 MeV, $8.9 \times 10^7 e/cm^2 / pulse$

Sample: 180nm-thick single crystal Si



A high-quality MeV ED was observed!

Intensity profile of 620 pattern



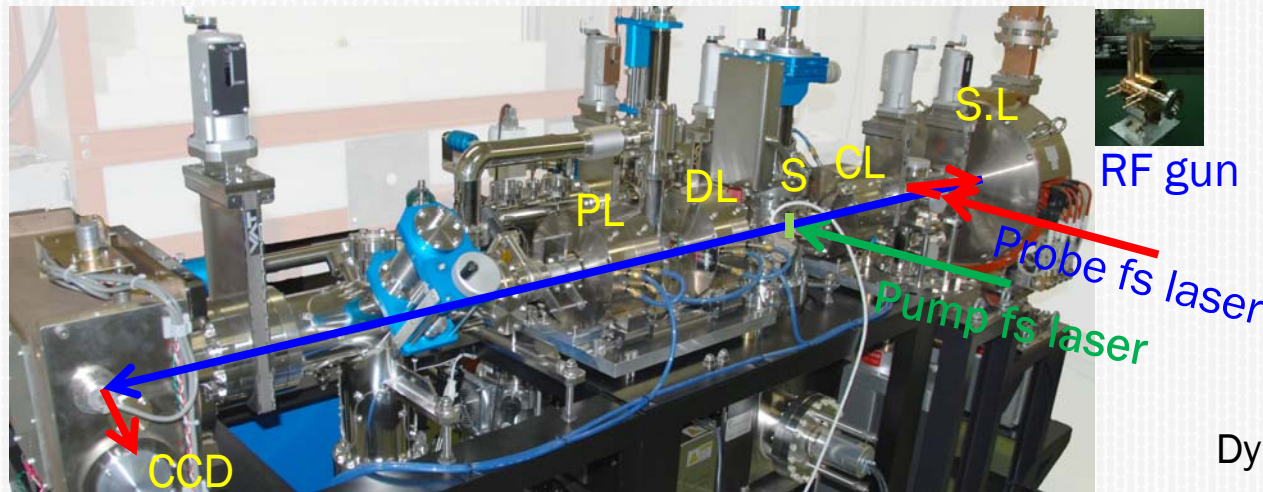
- Beam convergence angle: 0.05 mrad
- Maximum scattering vector : $q_{\max} > 1.56 \text{ \AA}^{-1}$
- Requirement of the e^- number: 10^{6-7}

- Bragg law

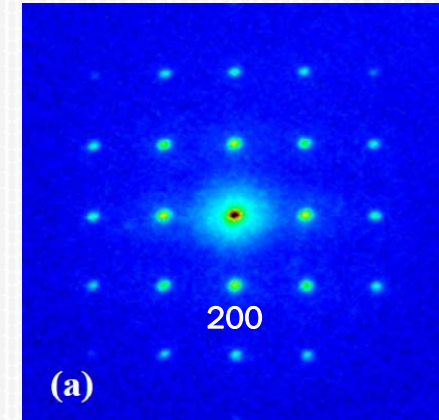
$$\begin{aligned} 2d \sin \theta &= n\lambda \\ \tan \theta &= \frac{D}{L} \end{aligned}$$

UED#2: Phase transformation on single-crystal Au

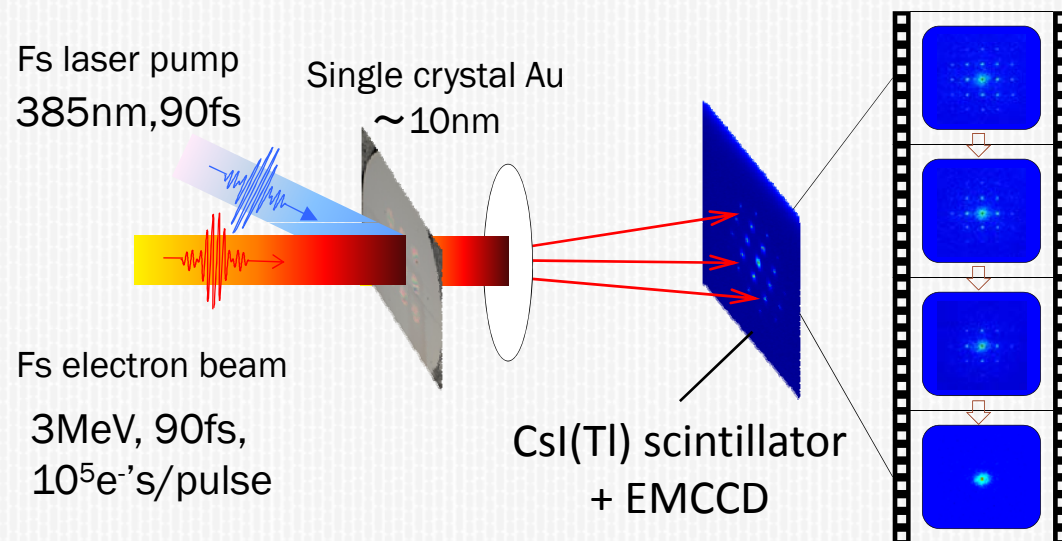
Femtosecond MeV electron diffraction at Osaka Univ.



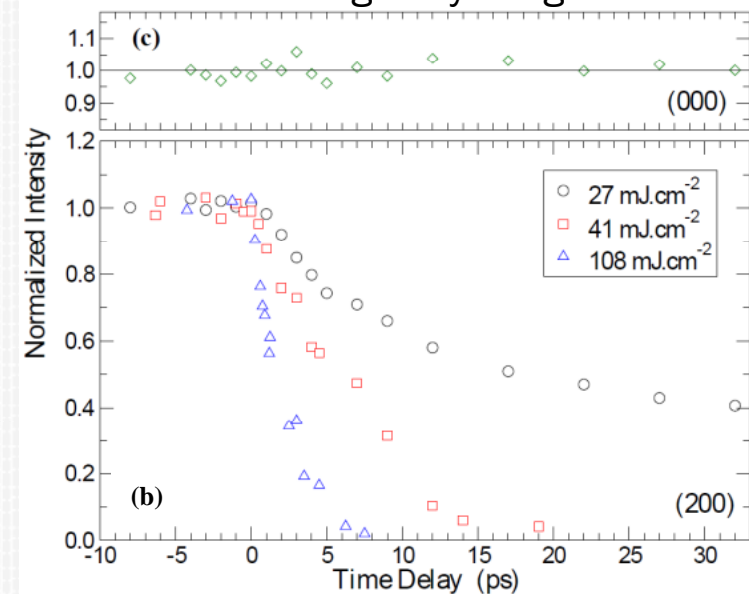
MeV electron diffraction
(Single-shot meas.)



Dynamics of laser-induced melting
on single crystal gold



PRB 2013; APL accepted.



Concluding remarks in UED

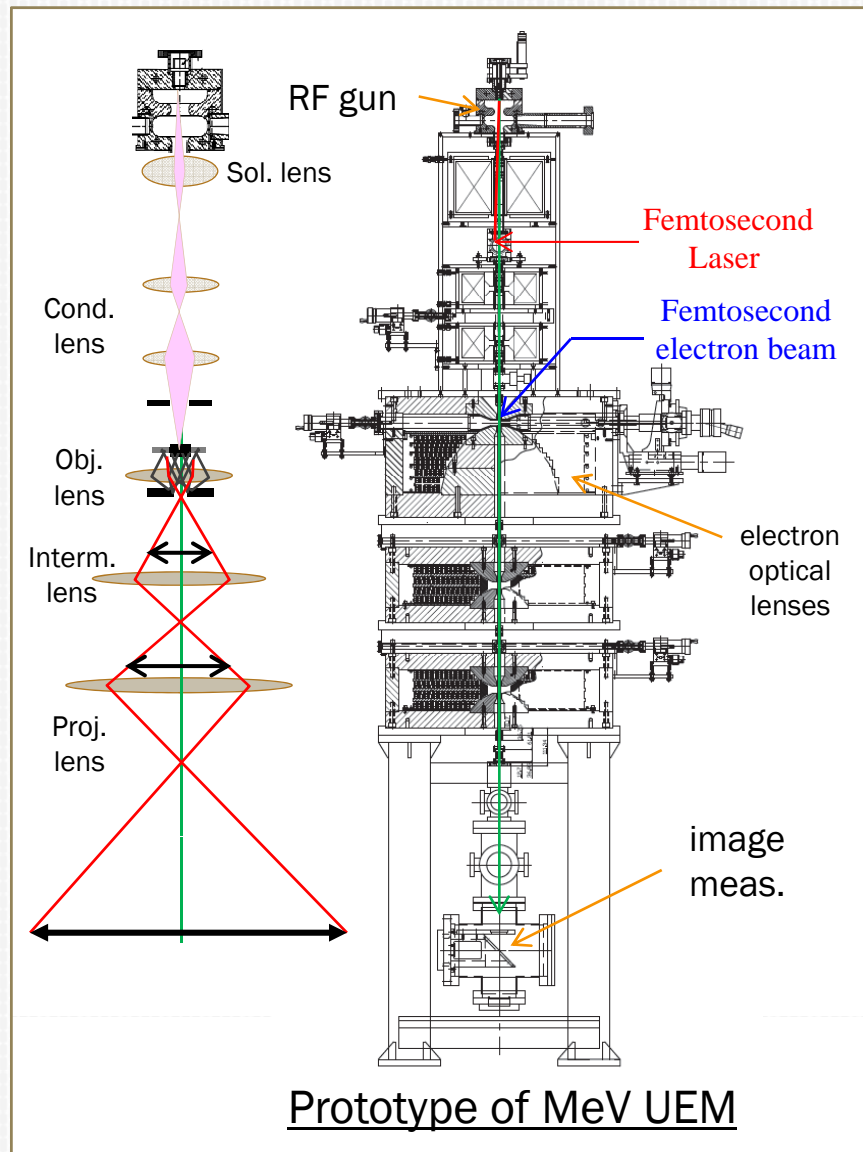
- The UED experiments indicate that the RF gun based MeV UED is useful tool for the study of ultrafast dynamics with time resolution of 100 fs or less.
- However,
 - Can RF gun be used in time-solved electron microscopy?
 - What kind efforts and challenges are needed?



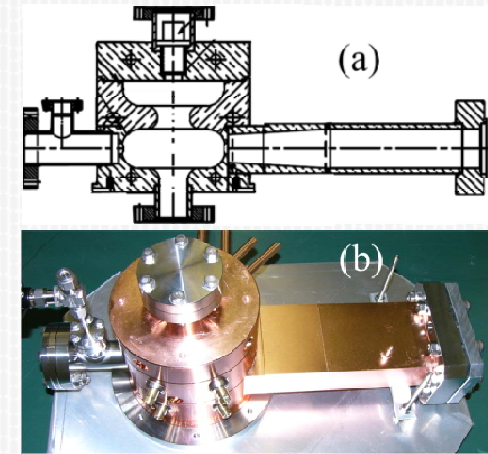
To answer the questions,
we developed a prototype of time-resolved TEM using RF gun.

Femtosecond time-resolved electron microscopy
using RF gun
(under development at Osaka Univ.)

Concept of RF gun based electron microscopy



Femtosecond
photocathode
electron gun



Electron energy : 1~3 MeV
Bunch length : 100 fs
Emittance : 0.1 mm-mrad
Energy spread : 10^{-4} (10^{-5} for challenge)
Charge : $10^7 \sim 10^8 e^-s/pulse$

Time resolution: 100 fs
Spatial resolution: 10 nm

Challenge!

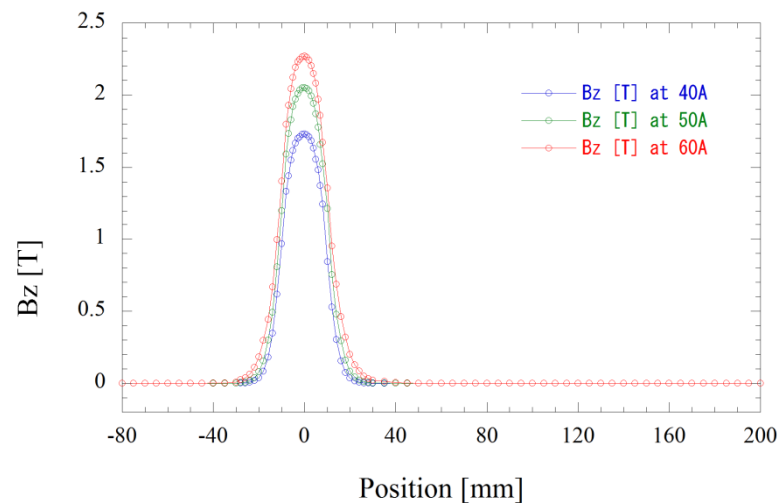
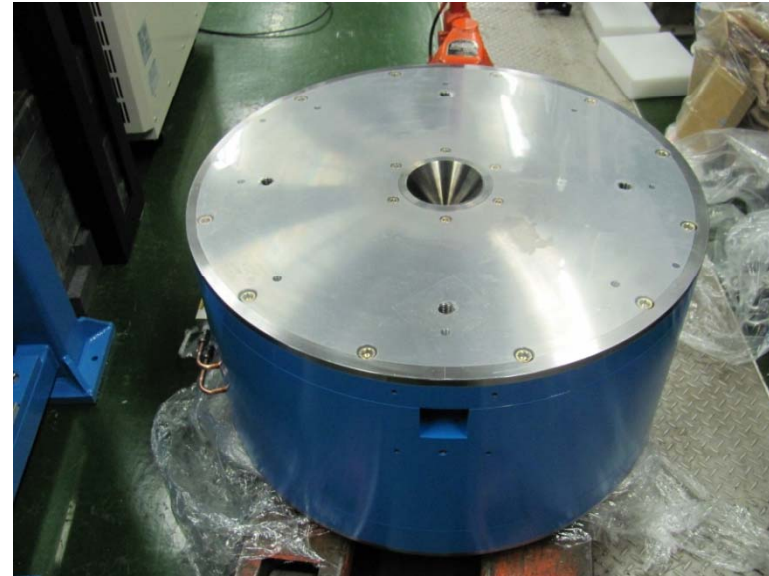
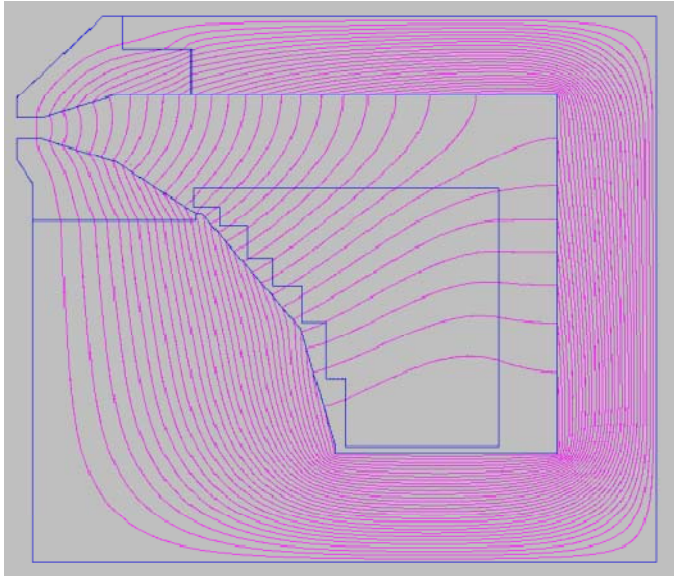
First prototype of RF gun based electron microscopy



Prototype of MeV UEM at Osaka Univ.
(height: 3m, diameter: 0.7m)

➤ The prototype was constructed at the end of Oct. 2012.

Design of 2T objective lens

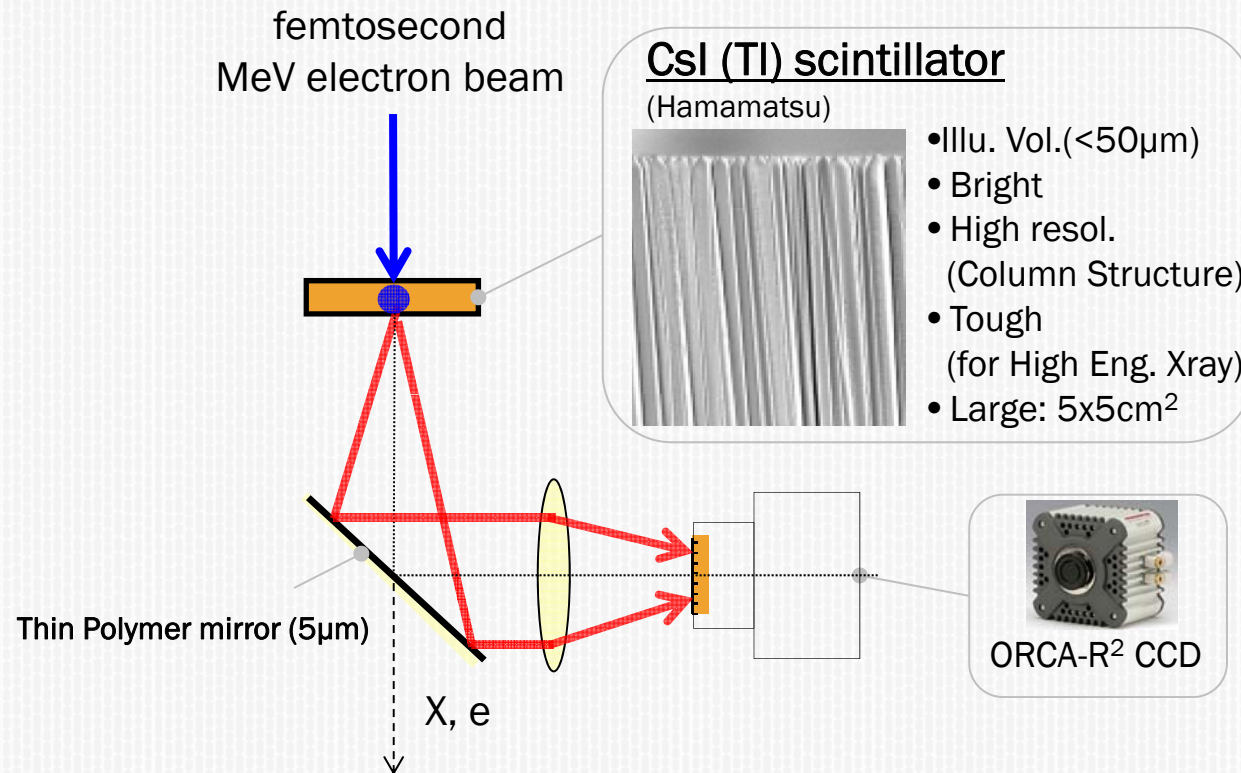


磁極口径 $\phi 13^{+0.05} \text{ mm}$
磁極長 350mm
磁場強度 2.2T
起磁力 35000 AT

$f_0 = 5 \text{ mm}$ for 2MeV e^-
 $C_s (C_c) \sim 4 \text{ mm}$

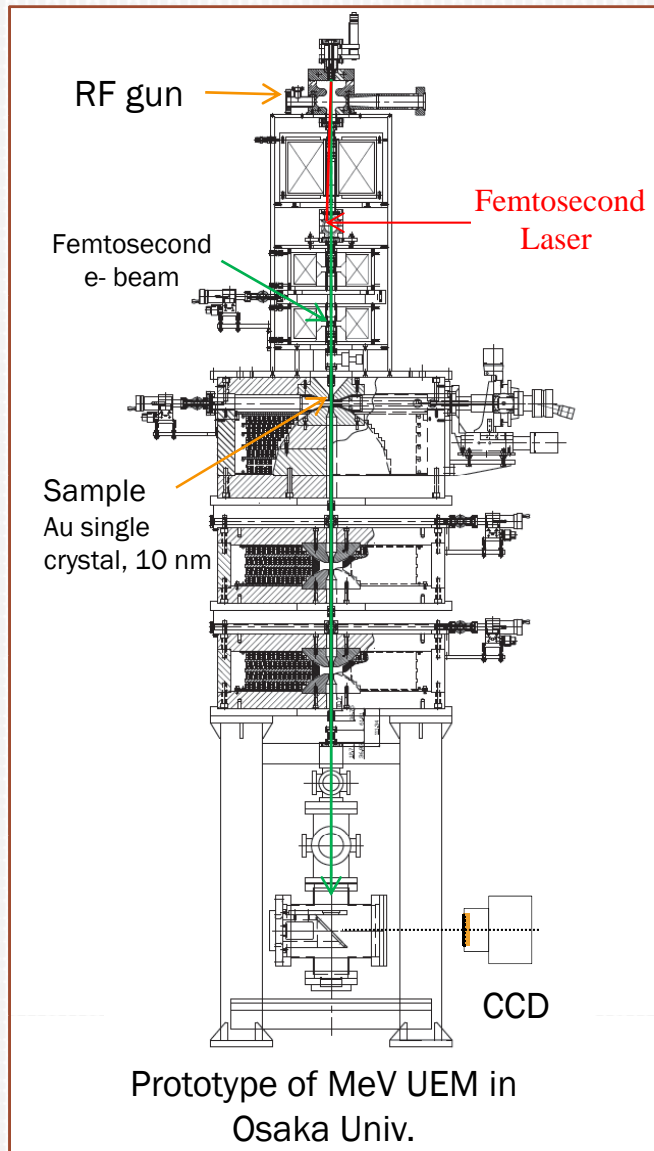
70 cm (D) x 35 cm (H)

Detection of MeV electron images

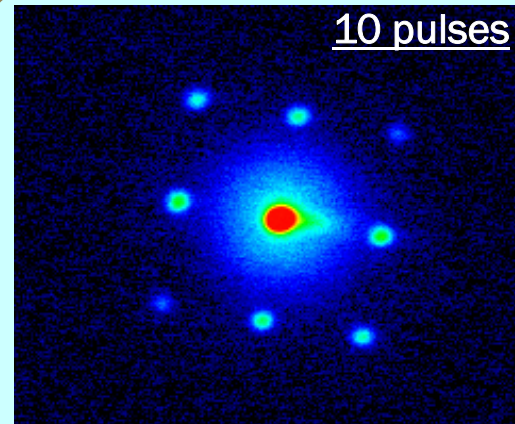


The detection system was successfully used in UED measurement.
(single-shot measurement with 10^5 e⁻/pulse)

Demonstrations of MeV ED/TEM imaging



MeV electron diffraction



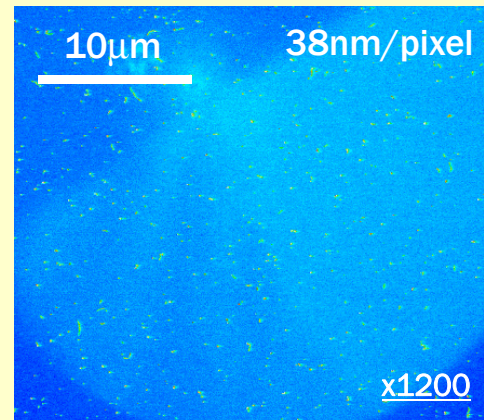
Sample: Au single-crystal film (10nm)

Electron energy: \sim MeV

Electron number:
 10^5 e-'s/pulse)

A good-quality MeV ED was observed at 10^6 e-'s/image!

Relativistic-energy TEM image

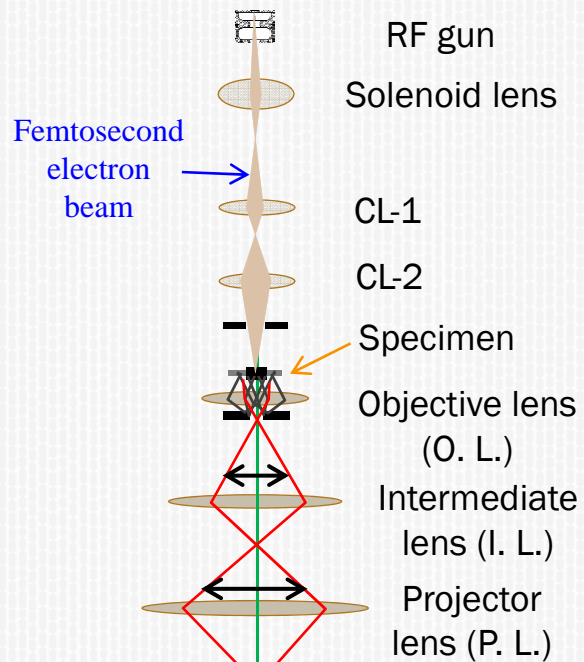


Electron charge:
 ~ 10 fC/pulse
(10^5 e-'s/pulse)

Measurement time:
 ~ 10 min

↓
 $\sim 10^8$ e-'s/image

Magnifications & resolutions

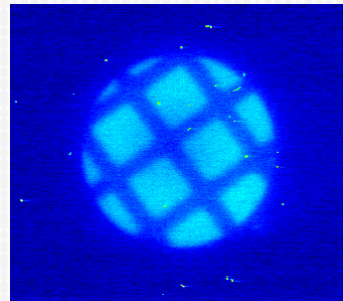


Spatial resolution

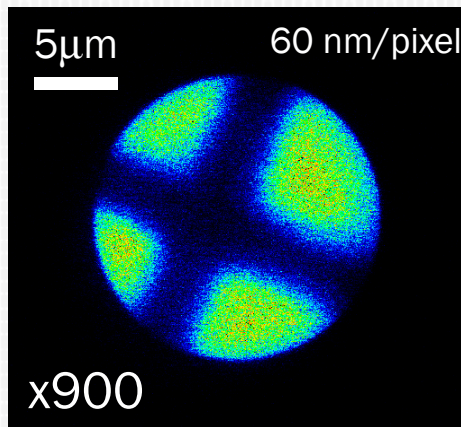
10nm (next step)
x10,000

~1nm (in future)

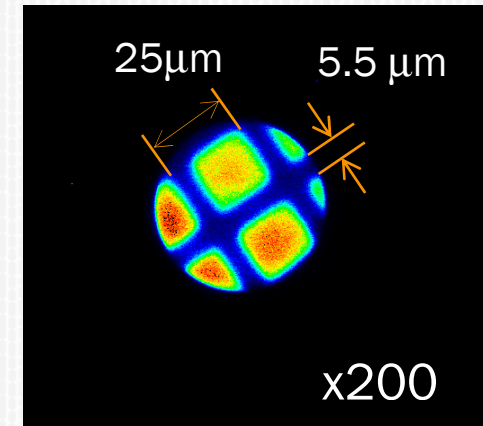
Sample:
Standard Cu grid(1000mesh)



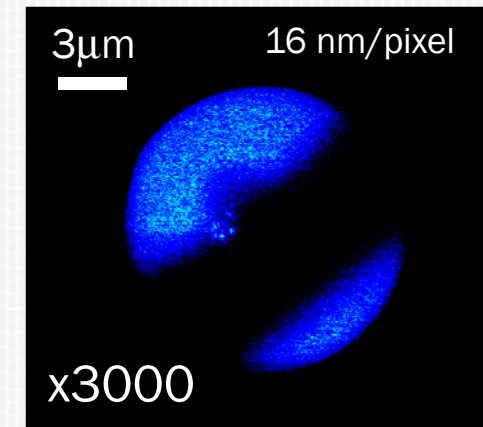
e^- energy: \sim MeV
 e^- number: $\sim 10^7$ /pulse



Using O.L. and I. L.



Using Obj. lens only



Using O.L., I. L. and P. L.

Conclusion and remarks

- ✓ Both RF gun based UED and UEM systems have been constructed at Osaka University.
- ✓ In UED, single-shot and time-resolved measurements have been succeeded. The time resolution was achieved to be 100 fs.
- ✓ In UEM, the MeV electron diffraction and imaging experiment was carried out. The resolution of 30 nm was achieved.
- ✓ Both experiments suggest that RF gun is very useful for ultrafast MeV electron diffraction and is also expected to be used in ultrafast electron microscopy.

However, great efforts and many challenges are required:

- reduce further the emittance ($<0.1 \mu\text{m}$) and energy spread (10^{-5} or less),
- increase the beam brightness,
- improve the stabilities on the charge and energy,
- develop a detection of very electron with MeV energy, and so on.